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INFORMATION DISCLOSURE STATEMENT BY APPLICANT May 29, 2009 <i>(use as many sheets as necessary)</i>		Application Number	10/529,369
		Filing Date	October 5, 2005
		First Named Inventor	H. MATSUTANI
		Art Unit	1796
		Examiner Name	Marc S. Zimmer
Sheet	1	of	1
		Attorney Docket Number	1303.44954X00

U.S. PATENT DOCUMENTS						
Examiner Initials ¹	Cite No. ¹	Document Number		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
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FOREIGN PATENT DOCUMENTS							
Examiner Initials ¹	Cite No. ¹	Foreign Patent Document		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ³ -Number ⁴ -Kind Code ⁵ (if known)					
/M.Z./		JP	2001-338978	12/07/2001	K. Furusawa, et al.		A
/M.Z./		JP	06-346025	12/20/1994	Y. Yamaho, et al.		A
/M.Z./		JP	2001-15496	01/19/2001	M. Tsunoda, et al.		A

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials ¹	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
/M.Z./		Japanese Official Action dated May 12, 2009, for Japanese Application No. 2003-317572.	
/M.Z./		Japanese Official Action dated April 28, 2009, for Japanese Application No. 2003-317568.	
/M.Z./		Y. Uchimar, et al., "Synthesis, Thin Film Formation and Evaluation of a Low-K Silicon-Borazine Polymer", <u>Polymer Preprints</u> , Vol. 51, No. 12 (2002), pp.3077-3078.	T
/M.Z./		H. Kame, "AIST has Developed Low-K Films Using Borazine-Silicon Polymer Material to Demonstrate Low Permittivity of 2.1 or Below", <u>Technology Semiconductor</u> , (2002), pp. 100-101.	T

Examiner Signature	/Marc Zimmer/	Date Considered	07/07/2009
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